

# TOCHIGI LAB.

## Direct observations of microscale deformation and fracture phenomena



Department of Fundamental Engineering

Nanoscale Strength of Materials  
Department of Mechanical Engineering, Graduate School of Engineering <https://sites.google.com/g.ecc.u-tokyo.ac.jp/nanoscale-strength>

### Development of atomic-resolution in situ TEM mechanical experiment system

Deformation and fracture of crystalline materials are originated from atomic displacements and atomic bond breaking. Transmission electron microscopy (TEM) is known to be one of superior techniques to directly observe the microstructures and atomic structures of matter. In situ TEM mechanical testing provides information on microstructural evolution and mechanical responses during deformation and fracture behavior. We are developing loading devices for in situ TEM mechanical testing based on MEMS technology and conducting applied in situ TEM experiments.

Fig. 1 shows a loading device for in situ TEM, atomic-resolution scanning TEM image under loading (sample: SrTiO<sub>3</sub>), and a strain map derived from the experimental image. These results indicate that our in situ experimental system has good stability to obtain fine atomic-resolution images under loading. In addition, the strain map shows a strong tensile strain is generated by stress concentration at the notch.

- T. Sato, E. Tochigi, T. Mizoguchi, Y. Ikuhara, H. Fujita, *Microelectro. Eng.* **164**, 43 (2016).
- E. Tochigi, T. Sato, N. Shibata, H. Fujita, Y. Ikuhara, *Microsc. Microanal.* **25**, S2, 770 (2019).
- E. Tochigi, T. Sato, N. Shibata, H. Fujita, Y. Ikuhara, *Microsc. Microanal.* **26**, S2, 1838 (2020).

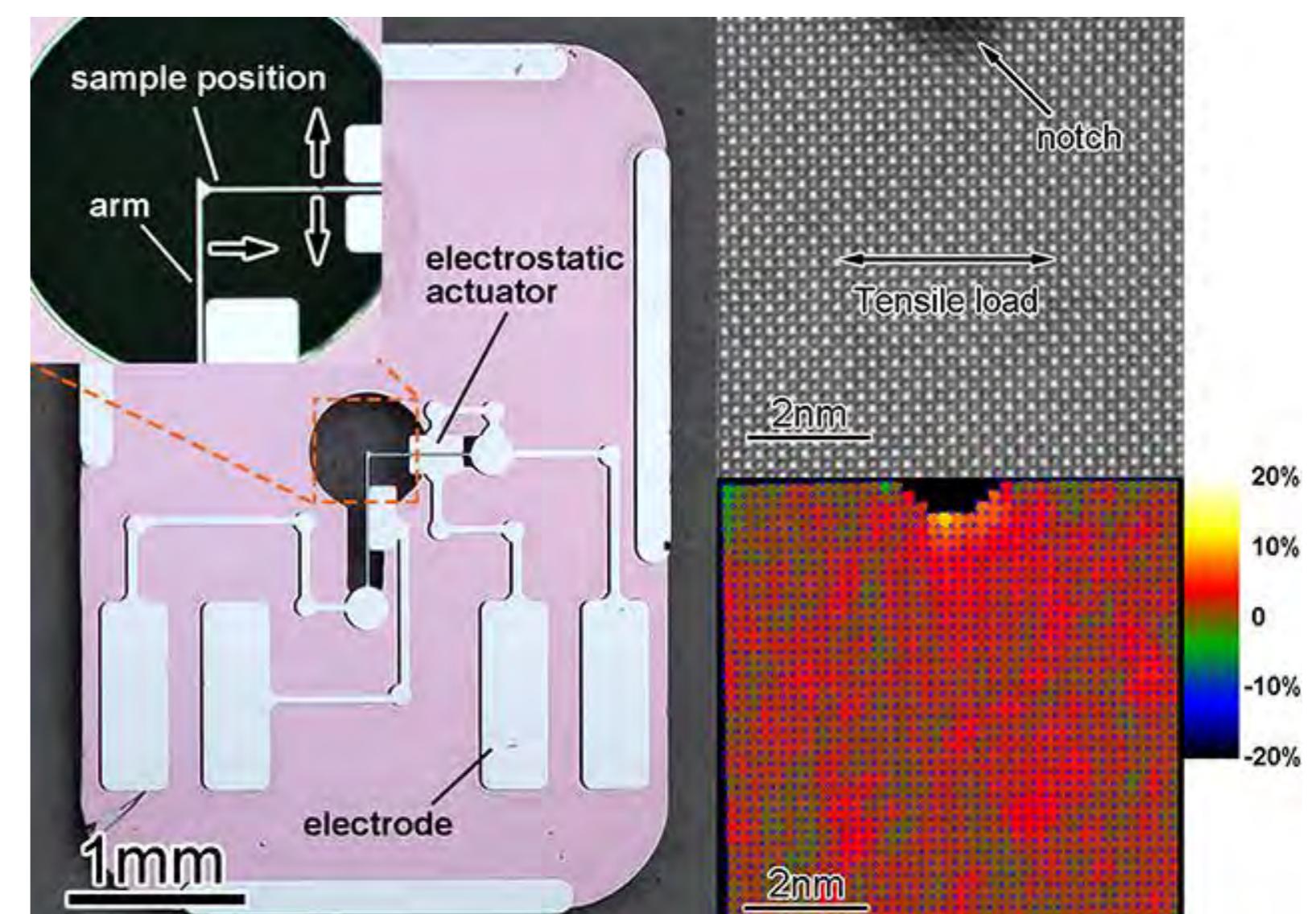


Fig. 1. Loading device fabricated by MEMS processes and atomic-resolution TEM tensile experiment of SrTiO<sub>3</sub> single crystal.

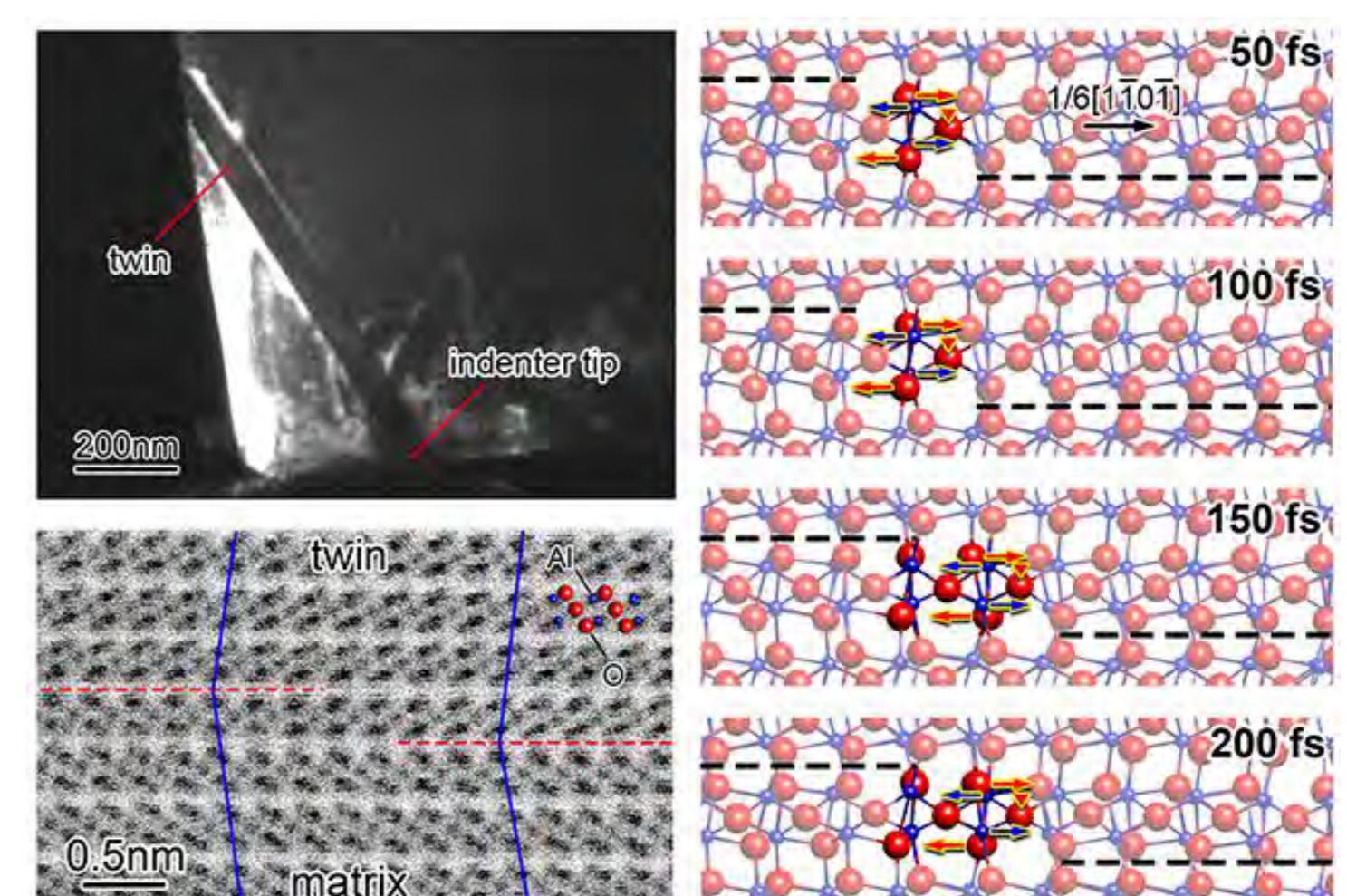


Fig. 2. In situ observations of twin in  $\alpha$ -Al<sub>2</sub>O<sub>3</sub>, interface atomic structure, and molecular dynamics simulation.

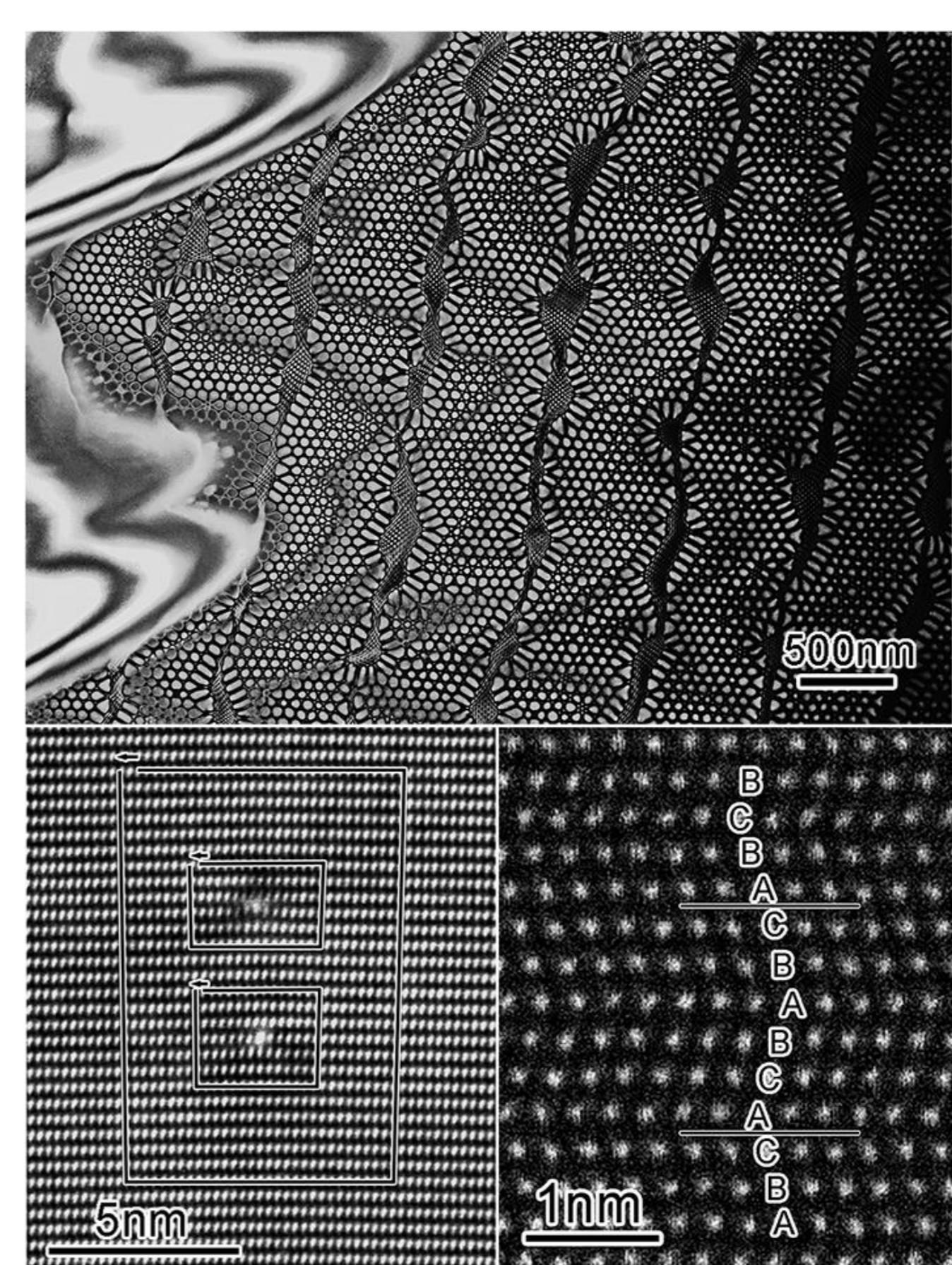


Fig. 3. Screw dislocation network ( $\alpha$ -Al<sub>2</sub>O<sub>3</sub>), dislocation core structure ( $\alpha$ -Al<sub>2</sub>O<sub>3</sub>), stacking fault (4H-SiC)